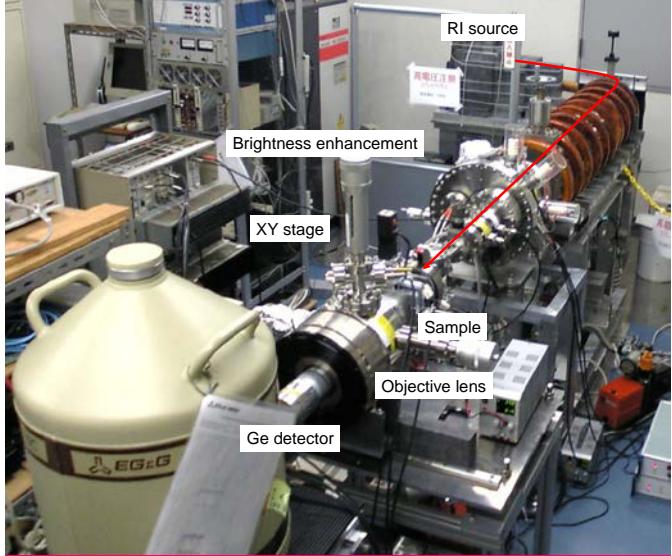


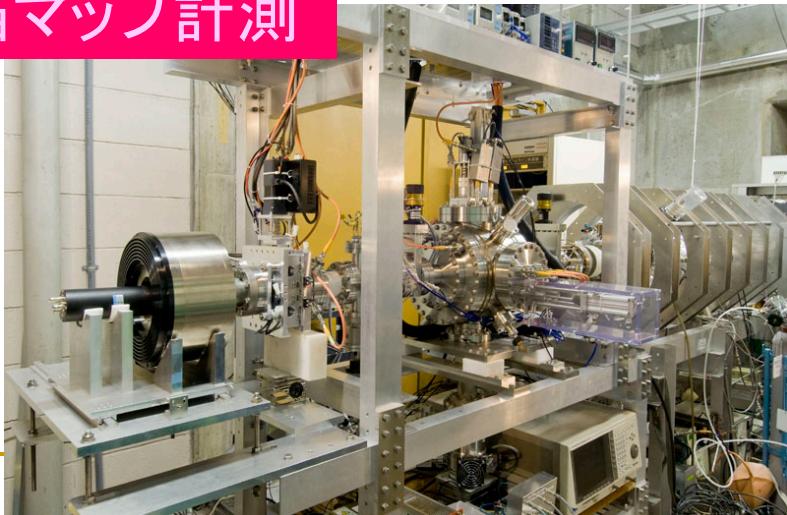
陽電子マイクロプローブによる3種類の陽電子顕微鏡の開発

Positron probe microanalyzer

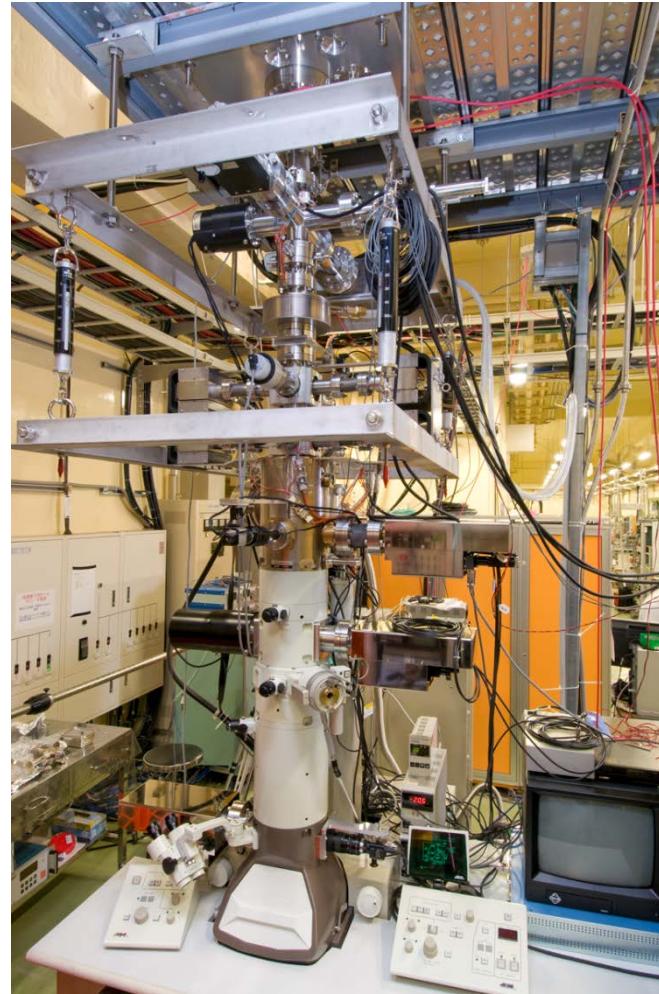


空孔型欠陥マップ計測

Linac-PPMA
@産総研



Transmission positron microscope

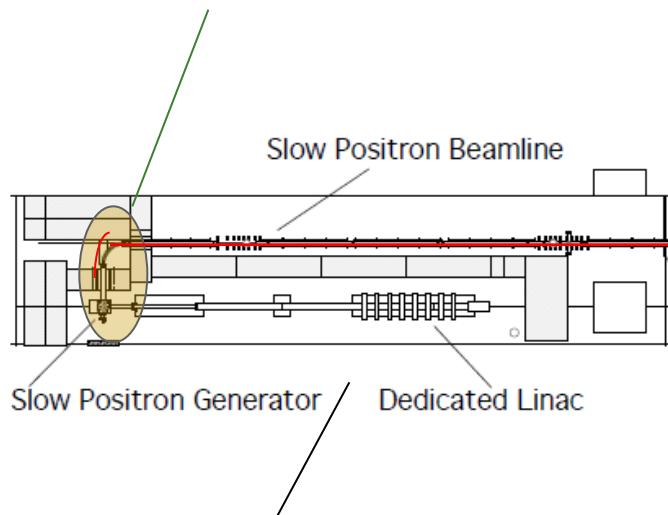


Linac-TPM
@KEK

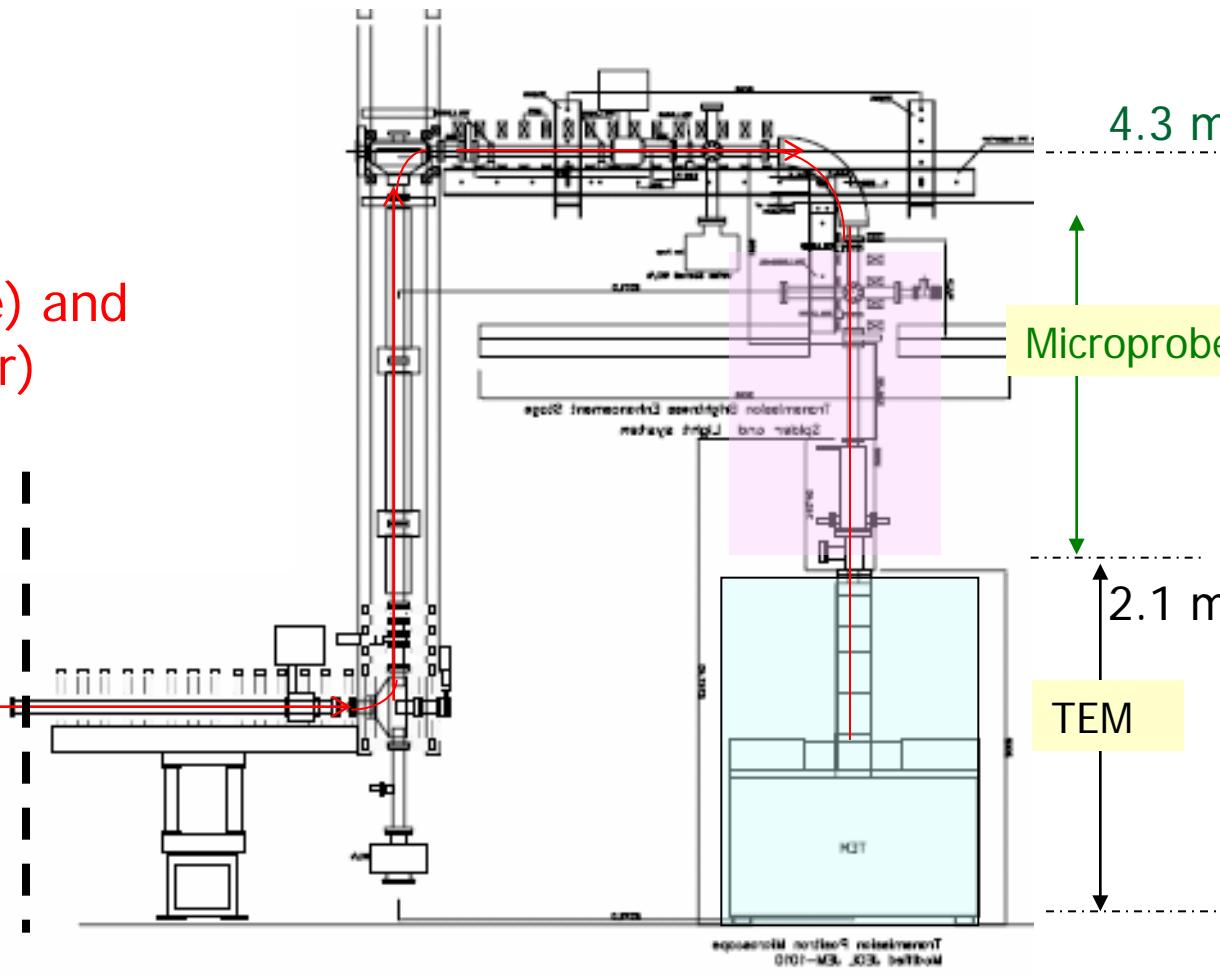
TEMとの差異

KEK-TPM 用陽電子ビームライン

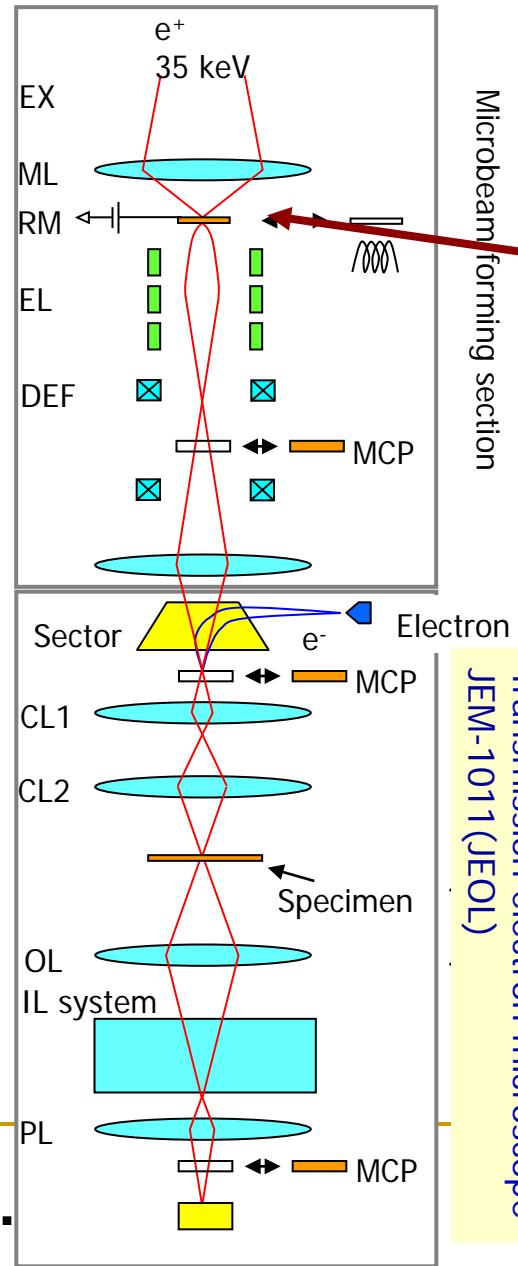
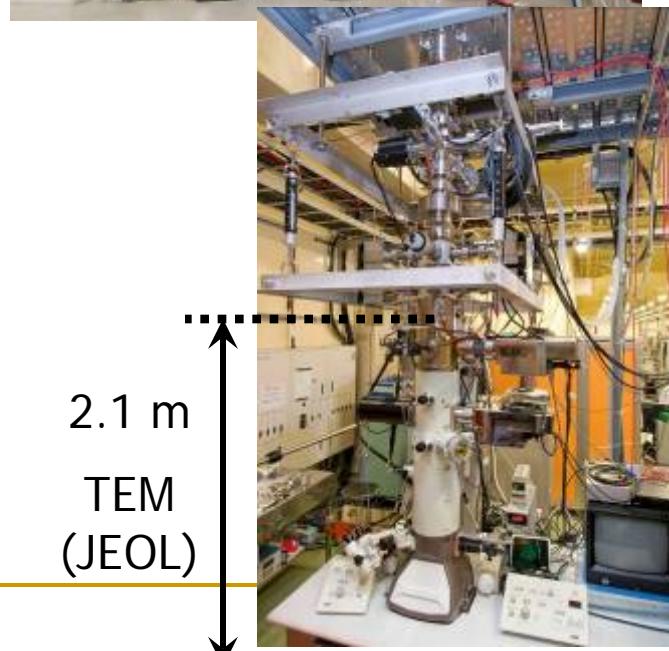
Ta target (positron source) and several W foils (moderator) floated at 35 kV



Linac : 44 MeV, 0.2 GeV·mA, 50 Hz

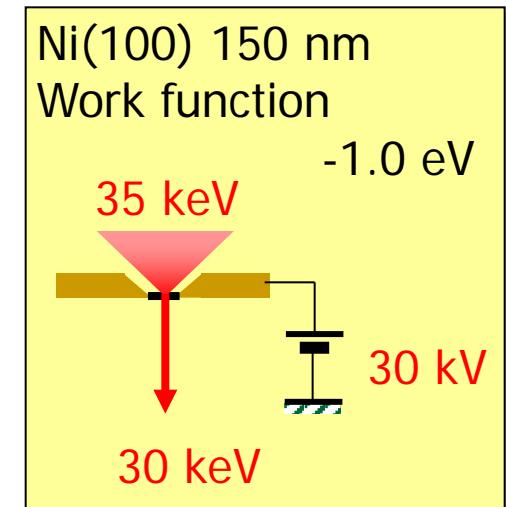


30 kV TPMのための陽電子光学系



Microbeam forming section

Transmission electron microscope
JEM-1011(JEOL)

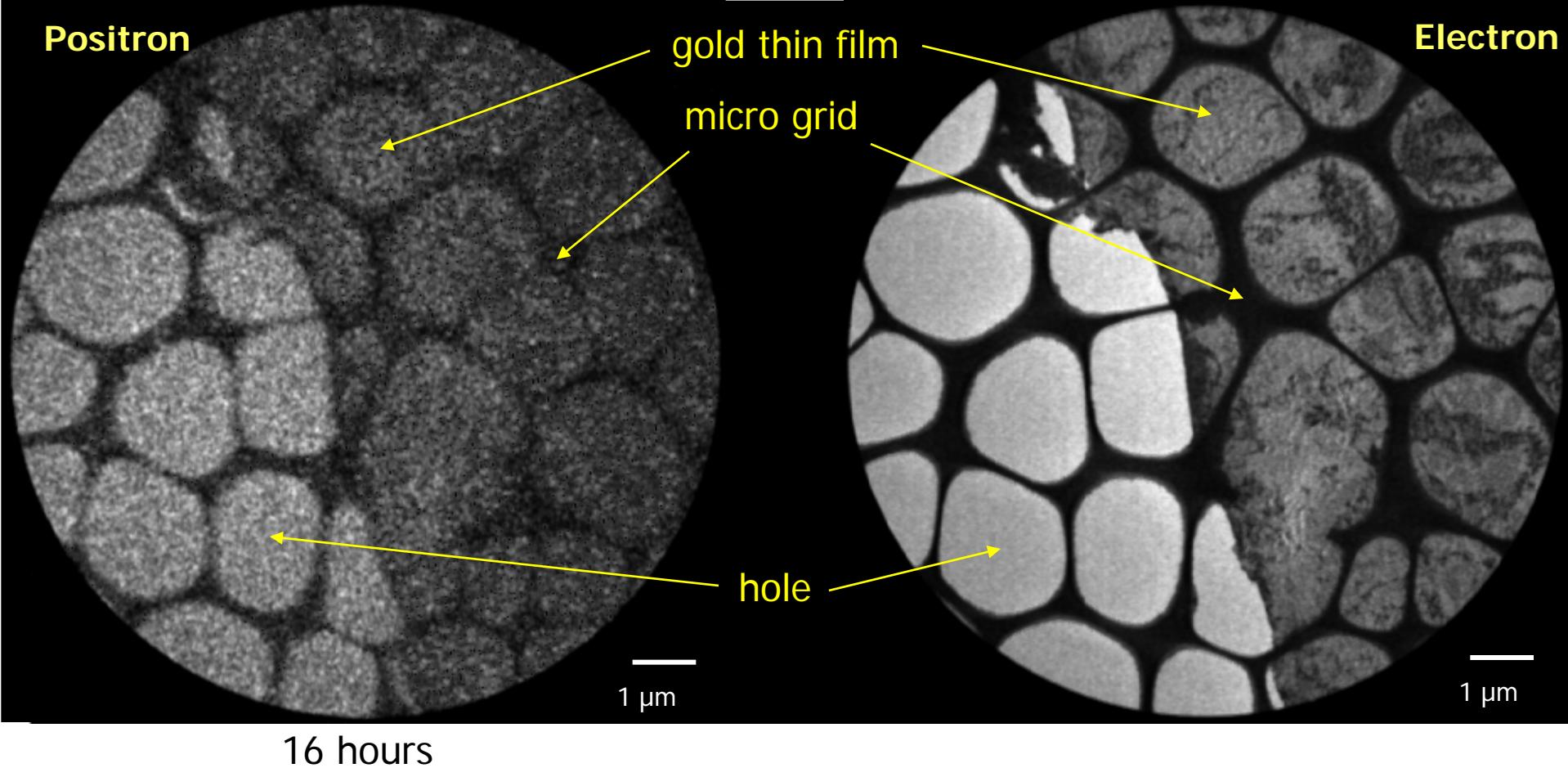


Remoderator

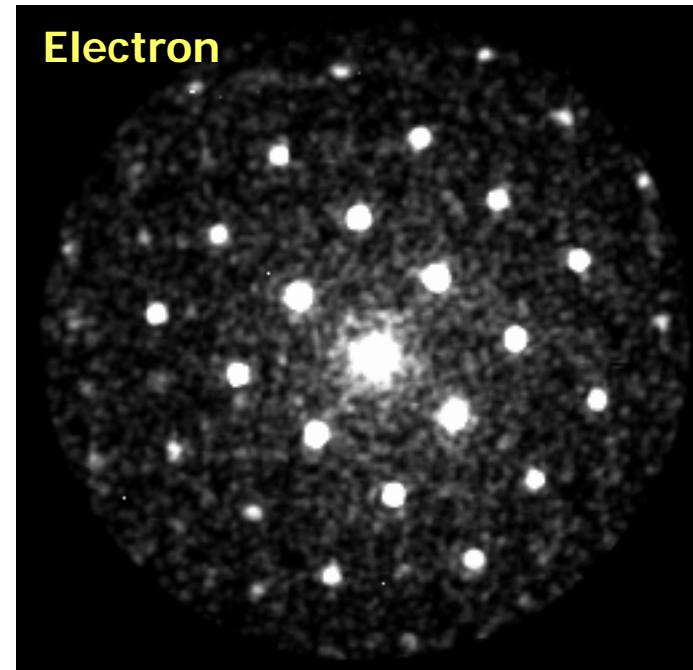
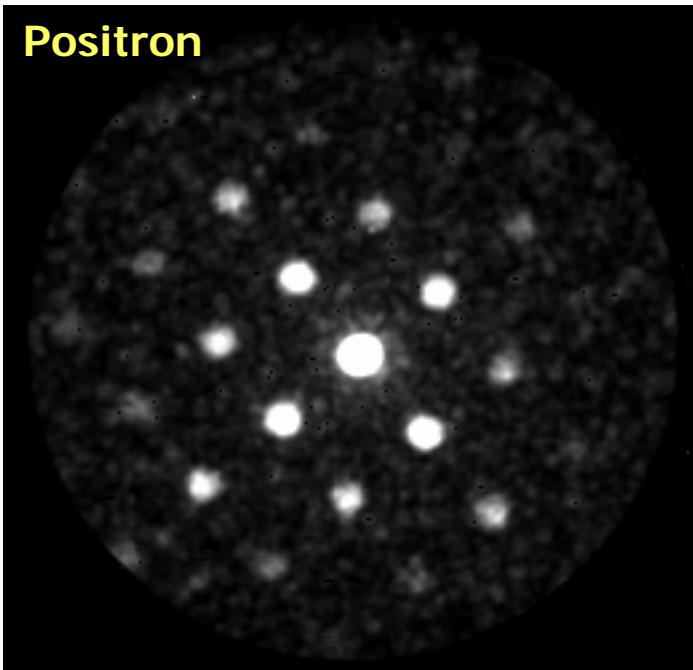
TPM & TEM image of Au(100) foil

Resolution : 50 nm

x10,000



e^+ & e^- diffraction pattern of Au(100) foil

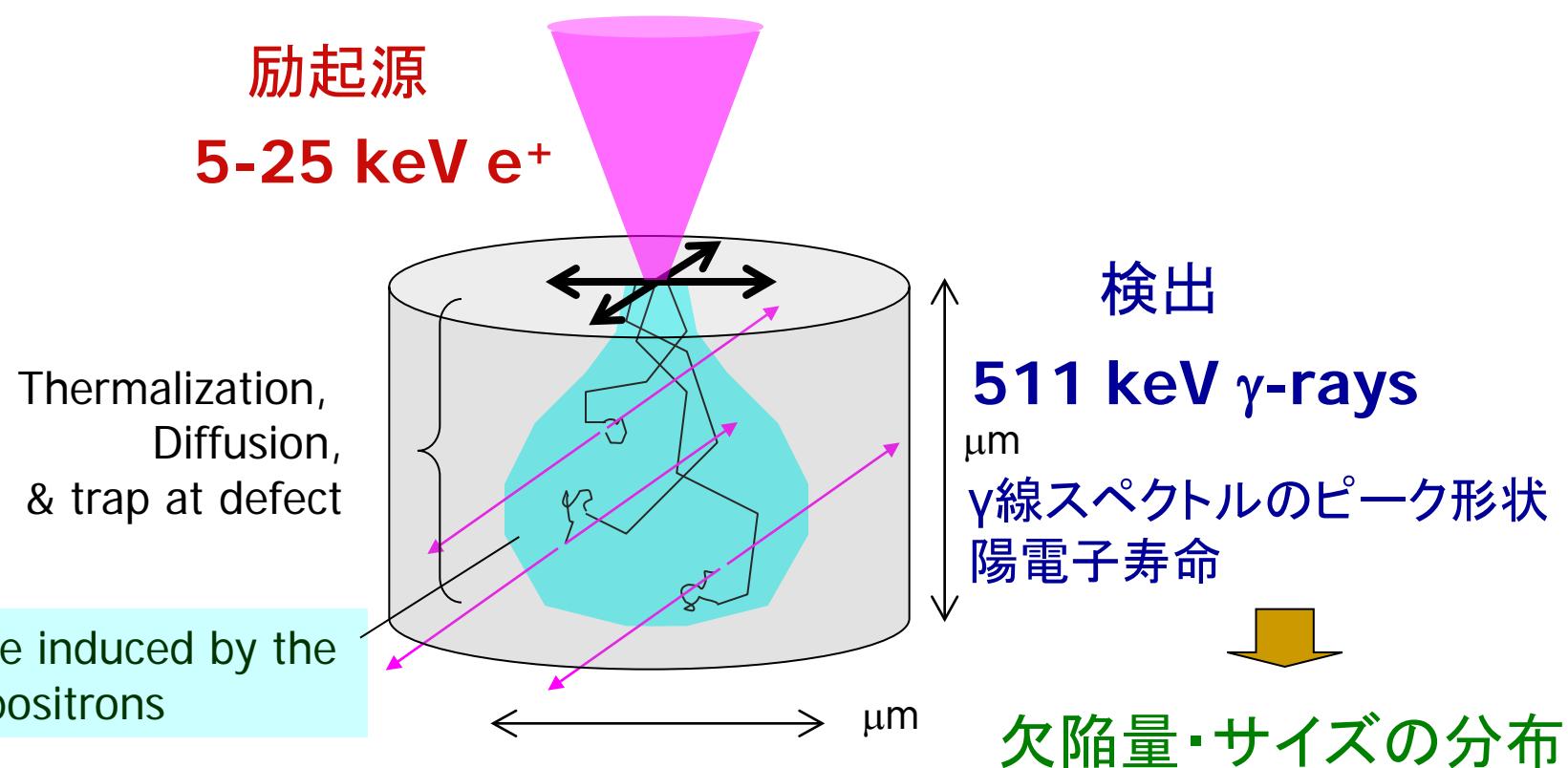


15 hr

We can succeed in 10,000 times TPM image and the diffraction pattern, comparable with TEM.

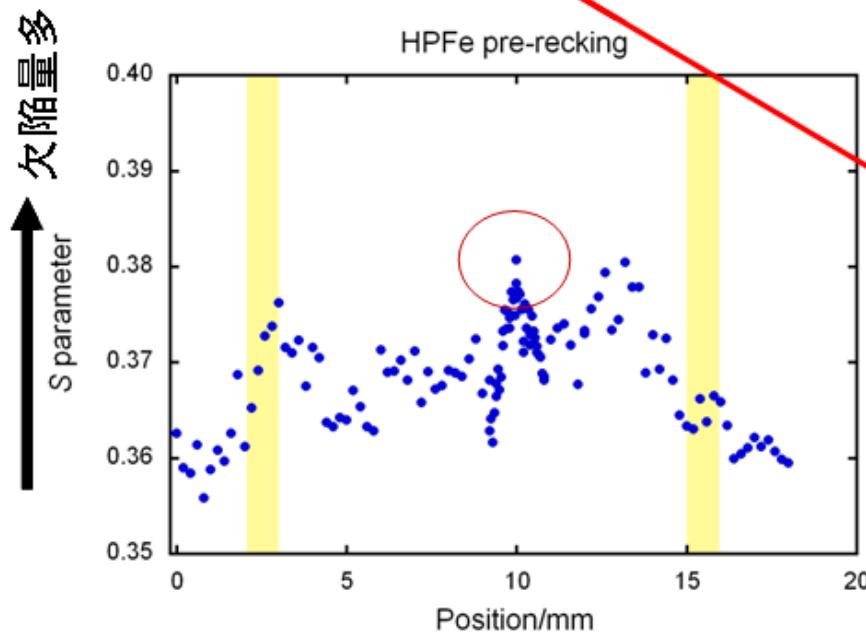
3. Positron probe microanalyzer (PPMA)

μm の空間分解能での欠陥マップ計測

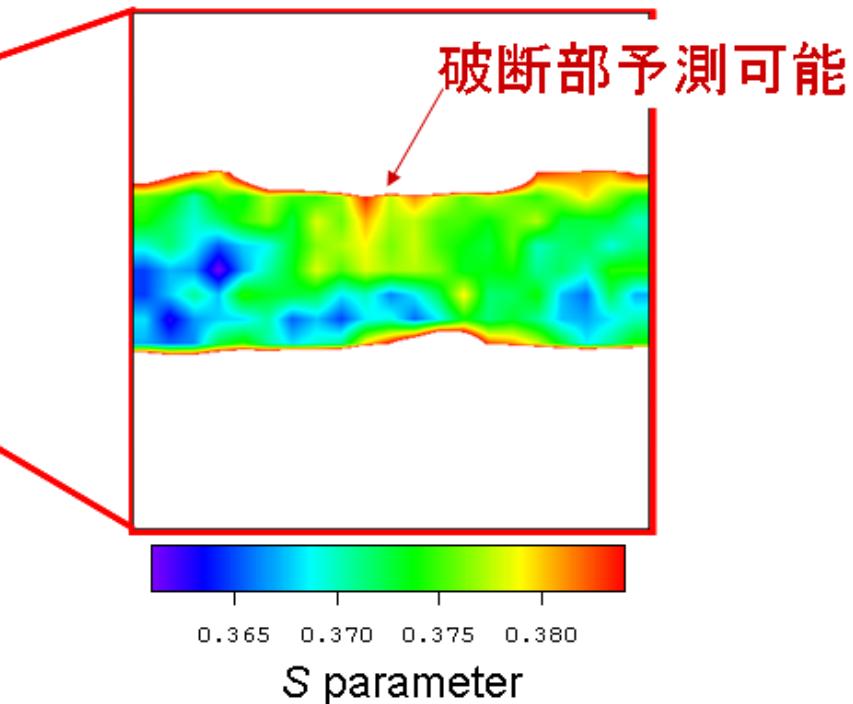


23%ひずみ導入純鉄の *S* マップ

200 $\mu\text{m}/\text{step}$
ピーク付近 50 $\mu\text{m}/\text{step}$
S parameter ($\Delta E=0.70 \text{ keV}$)



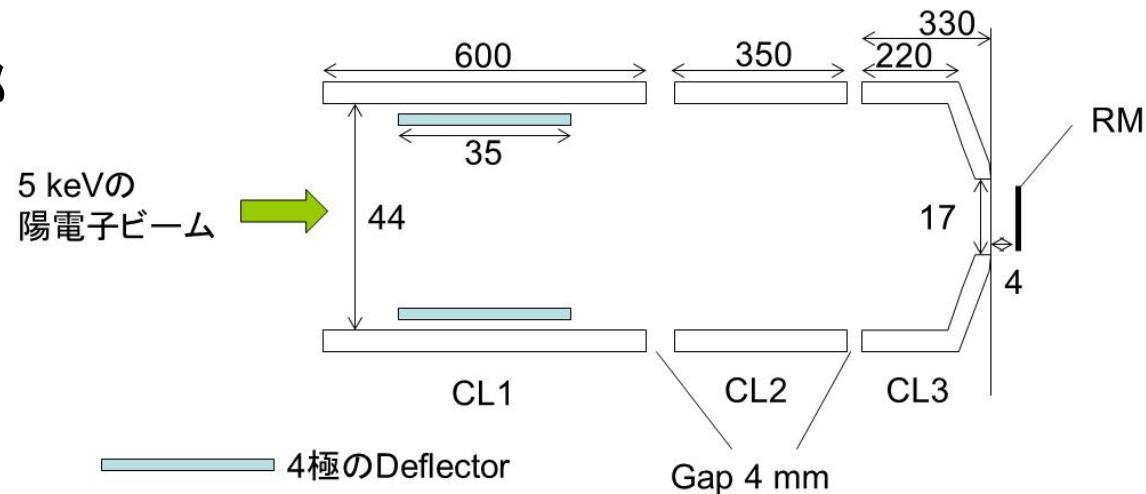
2 mm x 2 mm
100 $\mu\text{m}/\text{step}$



- ✓ 不均一な欠陥導入
- ✓ 局所的な欠陥濃度増大

提案する二段輝度増強LEPD光学系

● 二段目の輝度増強部



● 輝度増強後から入射ビーム形成の静電光学系

